

Notice of References Cited	Application/Control No. 09/916,701	Applicant(s)/Patent Under Reexam Ooi et al	
	Examiner Savitri Mulpuri	Art Unit 2812	Page 1 of 1

U.S. PATENT DOCUMENTS

	Document Number Country Code-Number-Kind Code	Date MM-YYYY ¹	Name	Classification ²	
A	6,027,989	2/2000	Poole et al	438	522
B	4,871,690	10/1989	Holonaya et al	438	46
C	20,020,127,752	9/2002	Thomson et al	438	22
D	5,757,023	5/1998	Koteles et al	257	18
E	5,238,868	8/1993	Elman et al	438	46
F					
G					
H					
I					
J					
K					
L					
M					

FOREIGN PATENT DOCUMENTS

	Document Number Country Code-Number-Kind Code	Date MM-YYYY ¹	Country	Name	Classification ²	
N						
O						
P						
Q						
R						
S						
T						

NON-PATENT DOCUMENTS

	Include, as applicable: Author, Title, Date, Publisher, Edition or Volume, Pertinent Pages
U	Lam et al "Plasma immersion Ar ions ion implantation induced disorder in strained InGaAsP multiple quantum wells" Electronic letters, April 1998 vol. 34 no. 8
V	Poole et al "Bandgap tuning of semiconductor quantum well structures using ion implantation", Superlattices and Microstructures vol. 15, no. 4 1994
W	
X	

* A copy of this reference is not being furnished with this Office action. See MPEP § 707.05(a).

¹ Dates in MM-YYYY format are publication dates.

² Classifications may be U.S. or foreign.